



## UNITED STATES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS  
UNITED STATES PATENT AND TRADEMARK OFFICE  
WASHINGTON, D.C. 20231  
www.uspto.gov

**\*BIBDATASHEET\***

Bib Data Sheet

**CONFIRMATION NO. 7420**

SERIAL NUMBER 10/706,944	FILING DATE 11/14/2003  RULE	CLASS 216	GROUP ART UNIT 1746	ATTORNEY DOCKET NO. 101136-00103
-----------------------------	---------------------------------------	--------------	------------------------	--

**APPLICANTS**

Takaiei Sasaki, Saitama-ken, JAPAN;

Noriyuki Harashima, Saitama-ken, JAPAN;

Satoshi Aoyama, Hyogo-ken, JAPAN; Shouichi Sakamoto, Hyogo-ken, JAPAN;

\*\* CONTINUING DATA \*\*\*\*\* *MK (Verified)*

This application is a DIV of 09/361,158 07/27/1999 PAT 6,685,848

\*\* FOREIGN APPLICATIONS \*\*\*\*\* *MK (Verified)*

JAPAN 309010/1998 10/29/1998

**IF REQUIRED, FOREIGN FILING LICENSE GRANTED**

\*\* 02/10/2004

Foreign Priority claimed 35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	STATE OR COUNTRY JAPAN	SHEETS DRAWING 7	TOTAL CLAIMS 2	INDEPENDENT CLAIMS 2
Verified and Acknowledged	Examiner's Signature <i>[Signature]</i> Initials				

**ADDRESS**

ARENT FOX KINTNER PLOTKIN & KAHN, PLLC  
SUITE 400  
1050 CONNECTICUT AVENUE, N.W.  
WASHINGTON, DC  
20036-5339

**TITLE**

Method and apparatus for dry-etching half-tone phase-shift films, half-tone phase-shift photomasks and method for the preparation thereof, and semiconductor circuits and method for the fabrication thereof

FILING FEE  RECEIVED 770	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____
-----------------------------------	---	--